



DFW

**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Attn: OIPE

Izumi FUSEGAWA et al.

Group Art Unit: 1722

Application No.: 10/510,695

Docket No.: 121356

Filed: October 8, 2004

For: METHOD OF MANUFACTURING SILICON SINGLE CRYSTAL, SILICON  
SINGLE CRYSTAL AND SILICON WAFER

**SECOND REQUEST FOR CORRECTION OF PALM RECORDS**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Attached is a photocopy of the original filing receipt on which an error has been corrected in red. This error is being brought to the attention of the Patent and Trademark Office so that it may correct its records.

Respectfully submitted,

William P. Berridge  
Registration No. 30,024

Jori B. Krischke  
Registration No. 57,349

WPB:JBK/rav

Date: July 25, 2006

**OLIFF & BERRIDGE, PLC**  
**P.O. Box 19928**  
**Alexandria, Virginia 22320**  
**Telephone: (703) 836-6400**

<p style="text-align: center;"><b>DEPOSIT ACCOUNT USE AUTHORIZATION</b> Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461</p>
---

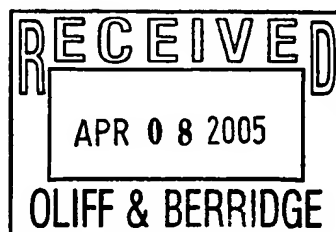


UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE  
 United States Patent and Trademark Office  
 Address: COMMISSIONER FOR PATENTS  
 P.O. Box 1450  
 Alexandria, Virginia 22313-1450  
 www.uspto.gov

APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/510,695	10/08/2004	1765	950	121356	3	9	3

25944  
 OLIFF & BERRIDGE, PLC  
 P.O. BOX 19928  
 ALEXANDRIA, VA 22320



CONFIRMATION NO. 3939  
 FILING RECEIPT



\*OC000000015631722\*

Date Mailed: 04/05/2005

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please mail to the Commissioner for Patents P.O. Box 1450 Alexandria Va 22313-1450. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

**Applicant(s)**

Izumi Fusegawa, Fukushima, JAPAN;  
 Sadayuki Okuni, Fukushima, JAPAN;  
 Nobuaki Mitamura, Fukushima, JAPAN;  
 Tomohiko Ohta, Fukushima, JAPAN;  
 Nobuo Katuoka, Fukushima, JAPAN;

**Assignment For Published Patent Application**

SHIN-ETSU HANDOTAI CO., LTD, Tokyo, JAPAN

**Power of Attorney:** The patent practitioners associated with Customer Number 25944.

**Domestic Priority data as claimed by applicant**

This application is a 371 of PCT/JP03/05167 04/23/2003

**Foreign Applications**

JAPAN 2002-122250 04/24/2002

**Projected Publication Date:** 07/07/2005**Non-Publication Request:** No**Early Publication Request:** No

Title

~~Method for producing silicon single crystal and, silicon single crystal and silicon wafer~~

Preliminary Class

117

METHOD OF MANUFACTURING SILICON SINGLE  
CRYSTAL, SILICON SINGLE CRYSTAL AND  
SILICON WAFER

---

**LICENSE FOR FOREIGN FILING UNDER****Title 35, United States Code, Section 184****Title 37, Code of Federal Regulations, 5.11 & 5.15****GRANTED**

The applicant has been granted a license under 35 U.S.C. 184, if the phrase "IF REQUIRED, FOREIGN FILING LICENSE GRANTED" followed by a date appears on this form. Such licenses are issued in all applications where the conditions for issuance of a license have been met, regardless of whether or not a license may be required as set forth in 37 CFR 5.15. The scope and limitations of this license are set forth in 37 CFR 5.15(a) unless an earlier license has been issued under 37 CFR 5.15(b). The license is subject to revocation upon written notification. The date indicated is the effective date of the license, unless an earlier license of similar scope has been granted under 37 CFR 5.13 or 5.14.

This license is to be retained by the licensee and may be used at any time on or after the effective date thereof unless it is revoked. This license is automatically transferred to any related applications(s) filed under 37 CFR 1.53(d). This license is not retroactive.

The grant of a license does not in any way lessen the responsibility of a licensee for the security of the subject matter as imposed by any Government contract or the provisions of existing laws relating to espionage and the national security or the export of technical data. Licensees should apprise themselves of current regulations especially with respect to certain countries, of other agencies, particularly the Office of Defense Trade Controls, Department of State (with respect to Arms, Munitions and Implements of War (22 CFR 121-128)); the Office of Export Administration, Department of Commerce (15 CFR 370.10 (j)); the Office of Foreign Assets Control, Department of Treasury (31 CFR Parts 500+) and the Department of Energy.

**NOT GRANTED**

No license under 35 U.S.C. 184 has been granted at this time, if the phrase "IF REQUIRED, FOREIGN FILING LICENSE GRANTED" DOES NOT appear on this form. Applicant may still petition for a license under 37 CFR 5.12, if a license is desired before the expiration of 6 months from the filing date of the application. If 6 months has lapsed from the filing date of this application and the licensee has not received any indication of a secrecy order under 35 U.S.C. 181, the licensee may foreign file the application pursuant to 37 CFR 5.15(b).